

WEST**Freeform Search**

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Term:

(CVD or plasma) and apparatus and (clean\$3 with
gas\$3)

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JPAB,EPAB,DWPL,TDBD	(CVD or plasma) and apparatus and (clean\$3 with gas\$3)	617	<u>L7</u>
USPT	((118/723R)!CCLS.)	412	<u>L6</u>
USPT	((118/723MP)!CCLS.)	182	<u>L5</u>
USPT	((118/726)!CCLS.)	956	<u>L4</u>
USPT	L2 and (clean\$3 with fluoride)	26	<u>L3</u>
USPT	L1 and (clean\$3 with gas\$3)	264	<u>L2</u>
USPT	((118/726/118/723R/118/723MP/118/723ME/118/723MR/118/723MA/118/723E)!CCLS.)	2271	<u>L1</u>